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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TORII, et al.

Serial No.: 09/917,912

Filed: July 31, 2001

For: METHOD AND APPARATUS FOR PROCESSING
SAMPLES

3B
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SUPPLEMENTAL PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

RECEIVED

October 29, 2001

NOV 2 2001

Sir:

TC 1700

Supplementing the Preliminary Amendment submitted July 31, 2001,
please amend the above-identified application, prior to examination thereof, as
follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

1. (Amended) A method of processing a semiconductor sample,
comprising the steps of:
- (i) etching the sample by means of a first plasma formed in a gas

10/30/2001 BSAYASI1 00000037 09917912

01 FC:102
02 FC:103

252.00 DP
144.00 DP

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